

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**DECLARATION FOR PATENT APPLICATION**

As a below named inventor, I hereby declare that:

My residence, post office address and citizenship are as stated below next to my name.

I believe I am an original, first and joint inventor of the subject matter which is claimed and for which a patent is sought on the invention entitled:

METHOD AND APPARATUS FOR CONTROLLING DEFECT FORMATION IN SILVER SELENIDE SPUTTERED FILMS

the specification of which is attached hereto.

I hereby state that I have reviewed and understand the contents of the above identified specification, including the claims, as amended by an amendment, if any, specifically referred to in this oath or declaration.

I acknowledge the duty to disclose all information known to me which is material to patentability as defined in Title 37, Code of Federal Regulations, § 1.56.

I hereby claim foreign priority benefits under Title 35, United States Code § 119/365 of any foreign application(s) for patent or inventor's certificate listed below and have also identified below any foreign application for patent or inventor's certificate having a filing date before that of the application on which priority is claimed:

Prior Foreign Application(s)	Priority Not <u>Claimed</u>		
_____ (Number)	_____ <input type="checkbox"/>		
_____ (Number)	_____ (Country)	_____ (Filing Date)	<input type="checkbox"/>
_____ (Number)	_____ (Country)	_____ (Filing Date)	<input type="checkbox"/>
_____ (Number)	_____ (Country)	_____ (Filing Date)	<input type="checkbox"/>

I hereby claim the benefit under Title 35, United States Code, § 120/365 of any United States and PCT international application(s) listed below and, insofar as

the subject matter of each of the claims of this application is not disclosed in the prior United States application in the manner provided by the first paragraph of Title 35, United States Code,

§ 112, I acknowledge the duty to disclose all information known to me to be material to patentability as defined in Title 37, Code of Federal Regulations, § 1.56(a) which became available between the filing date of the prior application and the national or PCT international filing date of this application:

(Application No.)	(Filing Date)	(Status) (patented, pending, abandoned)
(Application No.)	(Filing Date)	(Status) (patented, pending, abandoned)
(Application No.)	(Filing Date)	(Status) (patented, pending, abandoned)

I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

Please address all correspondence to Thomas J. D'Amico of **Dickstein Shapiro Morin & Oshinsky LLP** located at 2101 L Street NW, Washington, DC 20037-1526. Telephone calls should be made to (202) 785-9700.

Full name of first inventor: Jiutao Li

Inventor's signature: 

Date: 10/16/03

Residence: Boise, Idaho

Citizenship: China

Mailing Address: 5325 E. Branchwood Drive
Boise, Idaho 83716

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Signature Page for Second Inventor

Full name of second inventor: Allen McTeer

Inventor's signature:  Date: 10-21-03

Residence: Eagle, Idaho

Citizenship: US

Mailing Address: 208 N. Sierra View Way
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Jiutao Li, et al

Application No.: Not Yet Assigned

Group Art Unit: N/A

Filed:

Examiner: Not Yet Assigned

For: SILVER SELENIDE SPUTTER
DEPOSITION DEFECT FORMATION
AND CONTROL

**POWER OF ATTORNEY BY ASSIGNEE AND
CERTIFICATE BY ASSIGNEE UNDER 37 CFR § 3.73(B)**

Assistant Commissioner for Patents
Washington, DC 20231

Dear Sir:

Micron Technology, Inc., Assignee of the entire right, title and interest in the above-identified application by virtue of an Assignment, a copy which is attached hereto, hereby appoints the attorneys and agents of the firm of Dickstein Shapiro Morin & Oshinsky LLP located at 2101 L Street NW, Washington, DC 20037-1526, listed as follows:

Gary M. Hoffman	26,411	Ryan H. Flax	48,141	Ellen S. Tao	43,383
Thomas J. D'Amico	28,371	Richard LaCava	41,135	Gary L. Veron	39,057
Donald A. Gregory	28,954	John C. Luce	34,378	Steven I. Weisburd	27,409
James W. Brady, Jr.	32,115	Peter McGee	35,947	Mialeeka C. Williams-Bibbs	48,037
Jon D. Grossman	32,699	Edward A. Meilman	24,735	Peter Zura	48,196
Mark J. Thronson	33,082	Edwin Oh	45,319	Jeremy A. Cubert	40,399
Eric Oliver	35,307	William E. Powell, III	39,803	Gianni Minutoli	41,198
Laurence E. Fisher	37,131	Steven S. Rubin	43,063	Michael Bergman	42,318
Ian R. Blum	42,336	Michael J. Scheer	34,425	Salvatore P. Tamburo	45,153
Gabriela I. Coman	50,515	Stephen A. Soffen	31,063	Peter A. Veysman	45,920
Catherine A. Ferguson	40,877	Christopher M. Tanner	41,518	Christopher S. Chow	46,493

and also, listed as follows:

Charles B. Brantley, III	38,086	Kevin D. Martin	37,882	David J. Paul	34,692
Michael L. Lynch	30,871				

attorneys of Micron Technology, Inc. as its attorneys with full power of substitution to prosecute this application and to transact all business in the Patent and Trademark Office in connection therewith.

The Assignee certifies that the above-identified assignment has been reviewed and to the best of the Assignee's knowledge and belief, title is in the assignee.

Please direct all correspondence regarding this application to the following:

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Respectfully submitted,

MICRON TECHNOLOGY, INC.



Michael L. Lynch
Chief Patent Counsel
Registration No. 30,871

Dated:

Nov 12, 2003